

EV318282305



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/298,160
Filing Date April 22, 1999
Inventor Dan G. Custer
Assignee Micron Technology, Inc.
Group Art Unit 1763
Examiner Allan W. Olsen
Attorney's Docket No. MI22-1172
Title: Polishing Systems, Method of Polishing Substrates, and Methods of Preparing
Liquids for Semiconductor Fabrication Processes

RESPONSE TO MAY 29, 2003 OFFICE ACTION

RECEIVED

OCT 07 2003

TC 1700

To: Mail Stop Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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Responsive to the Office Action dated May 29, 2003, Applicant amends
and remarks as follows:

AMENDMENTS

Underlines indicate insertions and ~~strikeouts~~ indicate deletions.